

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Wen-Ben CHOU et al.

Application No: 09/998,858

Filed: October 31, 2001

For: METHOD AND APPARATUS FOR NITRIDE  
SPACER ETCH PROCESS IMPLEMENTING - *IN SITU*  
INTERFEROMETRY ENDPOINT DETECTION AND  
NON-INTERFEROMETRY ENDPOINT MONITORING



Attorney Docket No: LAM2P295

Examiner: Chen, Kin Chan

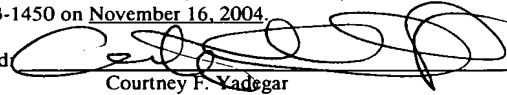
Group Art Unit: 1765

Date: November 16, 2004

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on November 16, 2004.

Signed

  
Courtney F. Yadegar

Mail Stop: AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

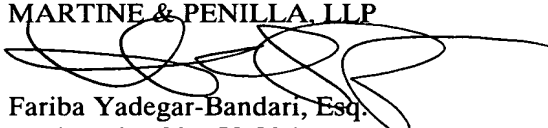
Transmitted herewith is an Amendment in the above-identified Application.

The fee has been calculated as shown below.

	Claims Remaining After <u>Amendment</u>	Highest Previously <u>Paid For</u>	Present <u>Extra</u>	<u>SMALL ENTITY</u> <u>RATE FEE</u>	OR	<u>LARGE ENTITY</u> <u>RATE FEE</u>
TOTAL CLAIMS	<u>18</u> -	<u>25</u>	<u>00</u>	X09 = \$ 0.00	OR	X18 = \$ 0.00
INDEP CLAIMS	<u>03</u> -	<u>08</u>	<u>00</u>	X43 = \$ 0.00	OR	X86 = \$ 0.00
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$145		\$290
<b>TOTAL</b>				<b>\$ <u>0.00</u></b>		<b>\$ <u>0.00</u></b>

- ☐ Applicant(s) hereby petition for a \_\_\_\_\_ month(s) extension of time to respond to the outstanding Office Action.
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805.
- ☐ Enclosed is our Check No. \_\_\_\_\_ in the amount of \$ \_\_\_\_\_ to cover the additional claim fee and/or extension of time fees.
- ☒ If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P295). A copy of this sheet is enclosed.

Respectfully submitted,  
MARTINE & PENILLA, LLP

  
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Response Under 37 C.F.R. § 1.116  
Expedited Procedure  
Examining Group 1765  
PATENT

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	)	Docket No. LAM2P295
Wen-Ben CHOU et al.	)	
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FOR NITRIDE SPACER ETCH	)	
PROCESS IMPLEMENTING -	)	
<i>IN SITU</i> INTERFEROMETRY	)	
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Signed: \_\_\_\_\_

Courtney F. Yadegar

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Dear Sir:

This is in response to the Final Office Action mailed on August 16, 2004. Please enter the following Amendments and remarks in the above-identified patent application:

Amendments to the claims are provided in the Listing of Claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.